

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner		Art Unit		Page 1 of 1
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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-2003/0057434	03-2003	HATA et al.	257/103
*	C	US-6,927,155	08-2005	Lugauer et al.	438/604
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Mayer et al, Electronic Materials Science: For Integrated Circuits in Si and GaAs, MacMillan Publishing, 1990, Page 433.
	V	Wikipedia entry on Metalorganic Vapour Phase Deposition.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.